



# Seiko Seiki STP-iX455

## Technical Specifications

Inlet flange size	ISO100K/DN100CF	ISO160K/DN160CF	
Pumping speed N <sub>2</sub>	300	450	litres/second
Pumping speed H <sub>2</sub>	300	460	litres/second
Compression ratio N <sub>2</sub>	>10 <sup>8</sup>	>10 <sup>8</sup>	
Compression ratio H <sub>2</sub>	1 x 10 <sup>4</sup>	1 x 10 <sup>4</sup>	
Ultimate pressure	6.5x10 <sup>-6</sup> (5x10 <sup>-8</sup> )	10 <sup>-8</sup> (10 <sup>-10</sup> )	Pa (Torr)
Maximum allowable backing pressure	67	67	Pa
Rated speed	55000	55000	rpm
Start time/Stop time	6/8	6/8	minutes
Mounting position	Any orientation		
Input voltage	48	48	V DC
Vibration levels	<0.01 (at rated speed)	<0.01 (at rated speed)	µm (0-P)
Noise levels	<50 (at rated speed)	<50 (at rated speed)	dB
Communication interface	I/O remote, RS232/485	I/O remote, RS232/485	
Maximum input power	240	240	W
Environment temperature during operation	0-40 (32-104)	0-40 (32-104)	°C (°F)
Weight	15 (33)	16 (35.2)	kg (lb)





# PROVAC

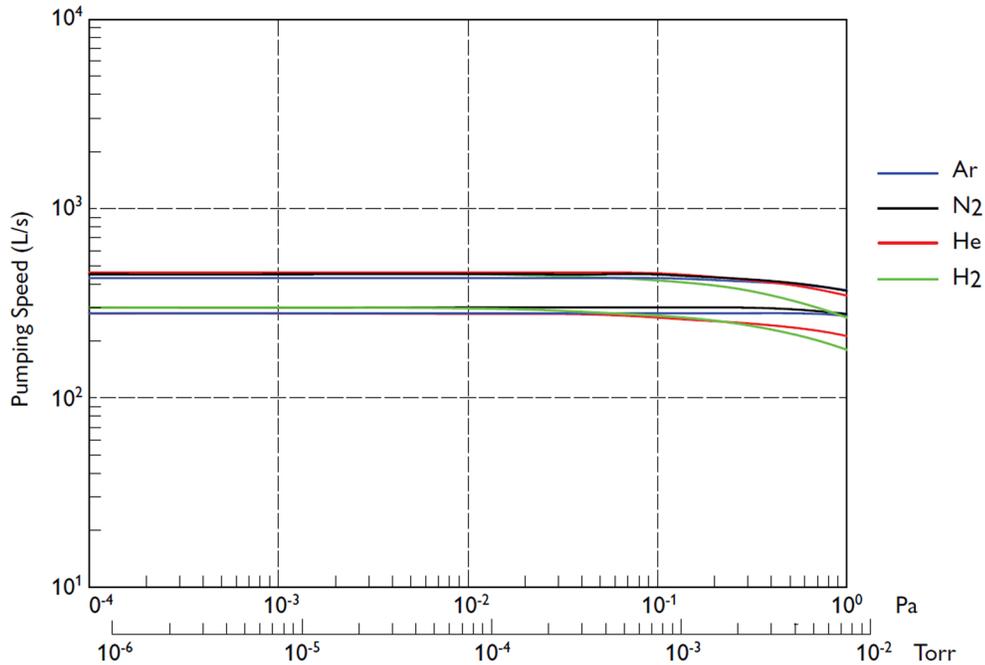
## SALES

PHONE: 831-462-8900

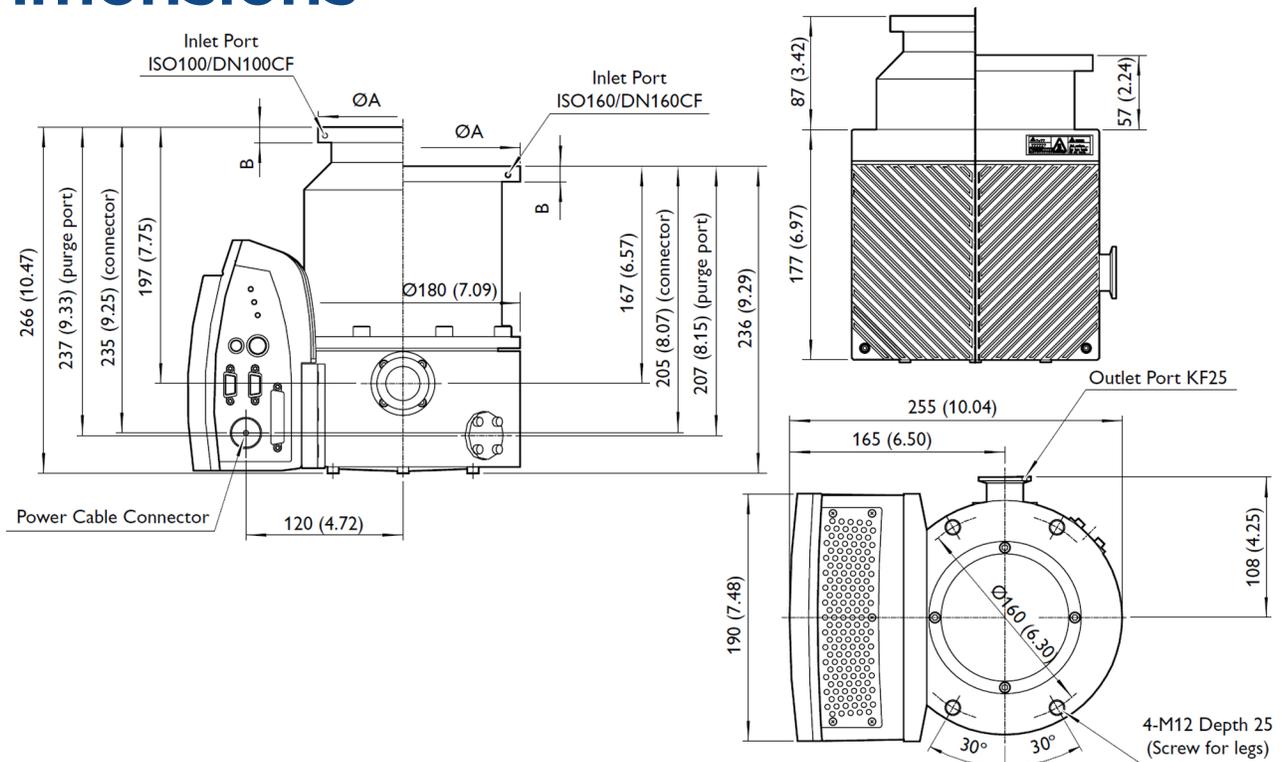
FAX: 831-462-3536

WWW.PROVAC.COM

# Seiko Seiki STP-iX455 Pumping Curves



## Dimensions





# PROVAC

## S A L E S

PHONE: 831-462-8900

FAX: 831-462-3536

WWW.PROVAC.COM

---

## Seiko Seiki STP-iX455

### Features & Benefits

- compact design with fully integrated controller
- innovative, self-sensing magnetic bearing system
- digital 5-axis control
- vibration levels reduced 50% compared to existing turbos
- can be configured to run corrosive processes
- automatic balancing system
- automatic vibration reduction
- maintenance free
- no need for water cooling

### Applications

- electron microscopy • metrology • lithography • vibration-sensitive applications • plasma etch • film deposition • sputtering • ion implantation source • photo resist stripping • load lock chambers
- surface analysis • mass spectrometry • high energy physics
- radioactive applications